PATENT Attorney Docket No.: SSI-00700

UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Maximilian A. Biberger et al.

Serial No.: 09/704,641

Filed: November 1, 2000

For:

METHOD AND APPARATUS FOR SUPERCRITICAL PROCESSING

OF A WORKPIECE

Group Art Unit:

Examiner:

INFORMATION DISCLOSURE **STATEMENT**

260 Sheridan Avenue, Suite 420 Palo Alto, California 94306 (650)833-0160

Assistant Commissioner for Patents Washington, D.C. 20231

Sir:

The citations listed below, copies attached, may be material to the examination of the above-identified application, and are therefore submitted in compliance with the duty of disclosure defined in 37 C.F.R. §§ 1.56 and 1.97. The Examiner is requested to make these citations of official record in this application.

Applicants have become aware of the following printed publications which may be material to the examination of this application:

- U.S. Patent No. 2,617,719;
- U.S. Patent No. 3,890,176;
- U.S. Patent No. 3,900,551;
- U.S. Patent No. 4,029,517;
- U.S. Patent No. 4,091,643;
- U.S. Patent No. 4,341,592;
- U.S. Patent No. 4,474,199;
- U.S. Patent No. 4,475,993;
- U.S. Patent No. 4,601,181;
- U.S. Patent No. 4,693,777;
- U.S. Patent No. 4,749,440;
- U.S. Patent No. 4,788,043;

CERTIFICATE OF MAILING (37 CFR § 1.8(a))

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the U.S. Postal Service on the date chown below with sufficient postage as first class mail in an envelope addressed to the: Assistant Commissioner for Patents, Washington D.C. 20231

-1-

- U.S. Patent No. 4,838,476;
- U.S. Patent No. 4,865,061;
- U.S. Patent No. 4,879,004;
- U.S. Patent No. 4,923,828;
- U.S. Patent No. 4,924,892;
- U.S. Patent No. 4,944,837;
- U.S. Patent No. 4,960,140;
- U.S. Patent No. 4,983,223;
- U.S. Patent No. 5,011,542;
- U.S. Patent No. 5,013,366;
- U.S. Patent No. 5,068,040;
- U.S. Patent No. 5,105,556;
- U.S. Patent No. 5,143,103;
- U.S. Patent No. 5,158,704;
- U.S. Patent No. 5,174,917;
- U.S. Patent No. 5,185,058;
- U.S. Patent No. 5,185,296;
- U.S. Patent No. 5,193,560;
- U.S. Patent No. 5,213,619;
- U.S. Patent No. 5,215,592;
- U.S. Patent No. 5,225,173;
- U.S. Patent No. 5,236,602;
- U.S. Patent No. 5,237,824;
- U.S. Patent No. 5,261,965;
- U.S. Patent No. 5,266,205;
- U.S. Patent No. 5,267,455;
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- U.S. Patent No. 5,290,361;
- U.S. Patent No. 5,294,261;
- U.S. Patent No. 5,304,515;
- U.S. Patent No. 5,306,350;
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- U.S. Patent No. 5,316,591;
- U.S. Patent No. 5,334,332;
- U.S. Patent No. 5,334,493;
- U.S. Patent No. 5,337,446;
- U.S. Patent No. 5,352,327;
- U.S. Patent No. 5,355,901;
- U.S. Patent No. 5,356,538;
- U.S. Patent No. 5,368,171;
- U.S. Patent No. 5,370,740;
- U.S. Patent No. 5,377,705;
- U.S. Patent No. 5,401,322;
- U.S. Patent No. 5,403,621;
- U.S. Patent No. 5,417,768;
- U.S. Patent No. 5,456,759;
- U.S. Patent No. 5,470,393;
- U.S. Patent No. 5,482,564;
- U.S. Patent No. 5,494,526;
- U.S. Patent No. 5,500,081;
- U.S. Patent No. 5,501,761;
- U.S. Patent No. 5,514,220;
- U.S. Patent No. 5,522,938;
- U.S. Patent No. 5,526,834;
- U.S. Patent No. 5,533,538;
- U.S. Patent No. 5,547,774;
- U.S. Patent No. 5,550,211;
- U.S. Patent No. 5,580,846;
- U.S. Patent No. 5,589,105;
- U.S. Patent No. 5,632,847;
- U.S. Patent No. 5,635,463;
- U.S. Patent No. 5,637,151;
- U.S. Patent No. 5,641,887;
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- U.S. Patent No. 5,679,169;
- U.S. Patent No. 5,679,171;
- U.S. Patent No. 5,683,977;
- U.S. Patent No. 5,688,879;
- U.S. Patent No. 5,700,379;
- U.S. Patent No. 5,726,211;
- U.S. Patent No. 5,739,223;
- U.S. Patent No. 5,783,082;
- U.S. Patent No. 5,798,438;
- U.S. Patent No. 5,804,607;
- U.S. Patent No. 5,868,856;
- U.S. Patent No. 5,868,862;
- U.S. Patent No. 5,872,257;
- U.S. Patent No. 5,873,948;
- U.S. Patent No. 5,881,577;
- U.S. Patent No. 5,908,510;
- U.S. Patent No. 5,944,996;
- U.S. Patent No. 5,976,264;
- U.S. Patent No. 5,980,648;
- U.S. Patent No. 6,017,820;
- U.S. Patent No. 6,024,801;
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- European Publication No. EP 0 587 168 A1;
- European Publication No. EP 0 572 913 A1;
- European Publication No. EP 0 536 752 A2;
- European Publication No. EP 0 283 740 A2;
- European Publication No. EP 0 302 345 A2;
- European Publication No. EP 0 370 233 A1;
- European Publication No. EP 0 391 395;
- Japanese Patent Abstract JP 2-304941;
- Japanese Patent Abstract JP 727711;
- Japanese Patent Abstract JP 1045131;
- Japanese Patent Abstract JP 2-148841;

U.S. Department of

Patent and Trademark Office

Attorney Docket No.: SSI-00700

Serial No.: 09/704,641

INFORMATION DISCLOSURAL TEMENT BY APPLICANT (Use Several Sheets If Necessary)

Applicant: Maximilian A. Biberger et al.

Filing Date: November 1, 2000

Group Art Unit:

(37 CFR § 1.98(0))	

xaminer		Serial / Patent Number	Issue Date	Applicant / Patentee	Class	Subclass	Filing Date
Initials		2,617,719	11/11/52	Stewart	23	312	12/29/50
	AA AB	3,890,176	06/17/75	Bolon	156	2	12/17/73
	AB	3,900,551	08/19/75	Bardoncelli et al.	423	9	03/02/72
	AC	4,029,517	06/14/77	Rand	134	11	03/01/76
	AD_		05/30/78	Zucchini	68	18	02/17/77
	AE	4,091,643	07/27/82	Shories et al.	156	643	08/04/75
	AF	4,341,592	10/02/84	Blaudszun	134	105	11/09/82
	AG	4,474,199	10/09/84	Blander et al.	204	64T	08/15/83
	AH	4,475,993	07/22/86	Privat	68	18	11/17/83
	AI	4,601,181	09/15/87	Hazano et al.	156	345	11/27/85
	AJ	4,693,777	06/7/88	Blackwood et al.	156	646	05/12/87
	AK_	4,749,440	11/29/88	Kagiyama et al.	422	292	04/17/86
	AL	4,788,043	06/13/89	Rahn	228	180.1	11/12/87
	AM	4,838,476	09/12/89	Fowler et al.	134	108	07/22/83
	AN	4,865,061		Oesch et al.	203	895	05/04/88
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	AP	4,923,828	05/08/90	Kiba et al.	134	123	07/28/88
	AQ	4,924,892	05/15/90	Nishikawa et al.	156	. 646	02/28/89
	AR	4,944,837	07/31/90	Ishijima et al.	134	31	11/27/85
	AS	4,960,140	10/02/90	Gessner	134	25.4	10/24/89
	AT	4,983,223	01/08/91	Weil	134	38	07/21/88
	AU	5,011,542	04/30/91	Jackson et al.	134	1 _	12/07/88
	AV	5,013,366	05/07/91	Jackson	210	748	04/03/89
	AW	5,068,040	11/26/91	Kurokawa et al.	34	12	08/09/88
	AX_	5,105,556	04/21/92	Basso et al.	134	98.1	01/04/91
	AY	5,143,103	09/01/92	Fulton et al.	252	309	07/25/90
	AZ_	5,158,704	10/27/92	Monzyk	252	60	07/19/91
	BA	5,174,917	12/29/92	Cathey, Jr.	156	656	01/29/91
	BB	5,185,058	02/09/93		437	229	04/24/91
	BC	5,185,296	02/09/93	Morita et al.	134	56R	06/24/91
	BD	5,193,560	03/16/93	Tanaka et al.	134	1	11/30/89
	BE	5,213,619	05/25/93	Jackson et al.	134	1	01/22/91
	BF	5,215,592	06/01/93	Jackson	423	2	10/25/91
	BG	5,225,173	07/06/93	Wai	210	748	01/28/91
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	BI	5,237,824	08/24/93	Pawliszyn	134	1	08/28/92
	BJ	5,261,965	11/16/93	Moslehi			

EXAMINER:

Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

FORM PTO-1449 Commerce (Modified) INFORMATION DISCLOSURE ST. (Use Several Sheets (37 CFR § 1.98(b))		U.S. Department of Patent and Trademark Office TEVIENT BY APPLICANT		Attorney Docket No.: SSI-00700 Applicant: Maximilian A. Biberger et al		Serial No.: 09/704,641		
37 CFR § 1.9	98(b))	S THADENLY		U.S. PATENT DOO	CUMENTS			
	Π	Serial / Patent	Issue Date		ant / Patentee	Class	Subclass	Filing Date
Examiner Initials		Number	Issue Date			210	639	07/01/92
	BK	5,266,205	11/30/93		alton et al.	68	5	07/13/92
	BL	5,267,455	12/0/193		wees et al.	549	349	06/12/91
	BM	5,274,129	12/28/93		atale et al.	134	31	07/29/92
	BN	5,288,333	02/22/94		ınaka et al.	134	2	01/23/92
	во	5,290,361	03/01/94		vashida et al.	134	7	11/02/92
	BP	5,294,261	03/15/94		Dermott et al.	437	231	08/07/92
	BQ	5,304,515	04/19/94		Iorita et al.	134	22	04/27/92
	BR	5,306,350	04/26/94	<u>I</u>	Hoy et al.		61	06/01/92
	BS	5,313,965	05/24/94		Palen	134	34	08/10/92
	ВТ	5,316,591	05/31/94	ļ	Chao et al.	134	548	07/09/92
	BU	5,334,332	08/02/94	<u> </u>	Lee	252	463	09/29/93
	BV	5,334,493	08/02/94	<u> </u>	Fujita et al.	430		10/27/92
	BW	5,337,446	08/16/94		Smith et al.	15	21.1	07/10/92
	BX	5,352,327	10/04/94		Witowski	156	646	10/27/92
	BY	5,355,901	10/18/94	N	Mielnik et al.	134	105	10/21/91
	BZ	5,356,538	10/18/94		Wai et al.	210	634	
	CA	5,368,171	11/29/94		Jackson	134	147	07/20/92
	СВ	5,370,740	12/06/94		Chao et al.	134	1	10/01/93
	CC	5,377,705	01/03/95	Sı	mith, Jr. et al.	134	95.3	09/16/93
	CD	5,401,322	03/28/95		Marshall	134	13 🐴	06/30/92
	CE	5,403,621	04/4/95		Jackson et al.	427	255.1	10/01/93
	CF	5,417,768	05/23/95	S	mith, Jr. et al.	134	10	12/14/93
		5,456,759	10/10/95	Sta	anford, Jr. et al.	134	1	08/01/94
	CG	5,470,393	11/28/95		Fukazawa	134	<u>√3</u>	07/08/94
	CH	5,482,564	01/09/96		Douglas et al.	134	0 18	,06/21/94
	CI	5,494,526	02/27/96		Paranjpe	134	11	05/04/95
	CJ		03/19/96		Bergman	156	646.1	12/05/94
	CK	5,500,081	03/26/96		Evans et al.	156	344	10/18/94
 	CL	5,501,761	05/07/96		Wetmore et al.	134	22.18	12/09/92
	CM	5,514,220	06/04/96		O'Brien	134	11	08/08/94
	CN	5,522,938	06/18/96		Mielnik et al.	134	105	08/17/94
	CO	5,526,834	07/09/96		Marshall	134	104.4	12/01/94
	СР	5,533,538	08/20/96		Gimzewski et al.	428	694	09/01/93
<u></u>	CQ	5,547,774			DeCrosta et al.	528	480	12/17/92
ļ	CR	5,550,211	08/27/96		Hayashida et al.	510	175	01/09/95
	CS	5,580,846	12/03/96		DeSimone et al.	252	351	05/18/95
	CT	5,589,105	12/31/96		Date Considered	d·		

EXAMINER:

Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

FORM PTO-1449 (Modified)

(37 CFR § 1.98(b))

U.S. Department of Commerce Patent and Trademark Office

Attorney Docket No.: SSI-00700

Applicant: Maximilian A. Biberger et al.

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U.S. Department of Control of the Co

Filing Date: November 1, 2000

Group Art Unit:

HIS PATENT DOCUMENTS

Examiner Initials	Serial / Patent Number		Issue Date	Applicant / Patentee	Class	Subclass	Filing D	Date	
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	cv	5,635,463	06/03/97	Muraoka	510	175	07/19/	95	
	CW	5,637,151	06/10/97	Schulz	134	2	06/27/	94	
	cx	5,641,887	06/24/97	Beckman et al.	546	26.2	04/01/	94	
	CY	5,656,097	08/12/97	Olesen et al.	134	1	12/21/	94	
		5,665,527	09/09/97	Allen et al.	430	325	02/03/	97	
	CZ	5,679,169	10/21/97	Gonzales et al.	134	1.3	12/19/	95	
	DA		10/21/97	Saga et al.	134	3	03/06/	96	
	DB	5,679,171	11/04/97	Jureller et al.	510	286	03/06/	95	
	DC	5,683,977	11/18/97	DeSimone	526	89	02/17/	97	
	DD	5,688,879	12/23/97	Biebl	216	2	02/14/	'96	
	DE	5,700,379		Hedrick et al.	521	61~	03/21/	96	
	DF	5,726,211	03/10/98	DeSimone	526	89.5	09/18/	95	
	DG	5,739,223	04/14/98	DeSimone et al.	210	634	11/03/		
	DH	5,783,082	07/21/98	Sawan et al.	528	483	09/09/96		
	DI	5,798,438	08/25/98		521	64	10/16/97		
	DJ	5,804,607	09/08/98	Hedrick et al.	134	2		07/23/97	
	DK	5,868,856	02/09/99	Douglas et al.	134	S 26	07/31/9		
	DL	5,868,862	02/09/99	Douglas et al.	546	336			
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	DQ	5,944,996	08/31/99	DeSimone et al.	210	634			
	DR	5,976,264	11/02/99				11/30/98		
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	DT	6,017,820	01/25/00	Ting et al.	438	689	07/17/98		
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U.S. Department of Patent and Trademark Office Attorney Docket No.: SSI-00700

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TEMENT BY APPLICANT If Necessary)

INFORMATION

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	FB (Russick, E.M. et and Pollution Prev	al., "Supercritical car vention, ACS Sympos	rbon dioxide extraction sium Series, Vol. 670	on of solvent from micro pp. 255-269,21 Oct 19	omachined structure 997	s. Supercritical I	riulus EXIT	activii
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EXAMINER:

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U.S. Department of

Patent and Trademark Office

Attorney Docket No.: SSI-00700

Serial No.: 09/704,641

INFORMATION DISCLOSURE STATEMENT BY APPLICANT
(See Several Sheets Necessary) Applicant: Maximilian A. Biberger et al. PADEMAN Group Art Unit: Filing Date: November 1, 2000 (37 CFR § 1.98(b)) OTHER DOCUMENTS (Including Author, Title, Date, Relevant Pages, Place of Publication) Dahmen, N. et al., "Supercritical fluid extraction of grinding and metal cutting waste contaminated with oils, "Supercritical Fluids - Extraction and Pollution Prevention, ACS Symposium Series, Vol. 670, pp. 270-279, 21 Oct 1997 FC 1 Wai, C.M., "Supercritical fluid extraction: metals as complexes," J. Chromatograhy A, Vol. 785, pp. 369-383, 17 Oct 1997 FD Xu, C. et al., Submicron-sized spherical yttrium oxide based phosphors prepared by supercritical CO2-assisted aerosolization and pyrolysis," Appl. Phys. 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Respectfully submitted,

HAVERSTOCK & OWENS LLP

Dated: 3-14-01

Thomas B. Haverstock

Reg. No.: 32,571

Attorneys for Applicants